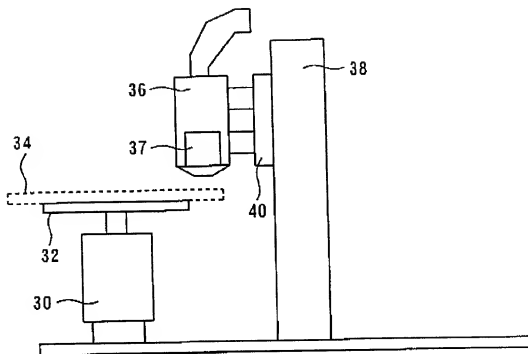


Fig. 1



Title: WAFER EDGE EXPOSURE
APPARATUS, AND WAFER EDGE
EXPOSURE METHOD
Inventor: Jeong Yeal KIM
Docket No.: 025311-0113

Fig.2

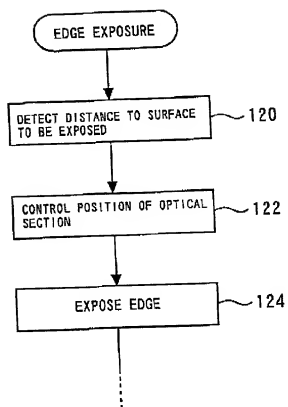


Fig.3

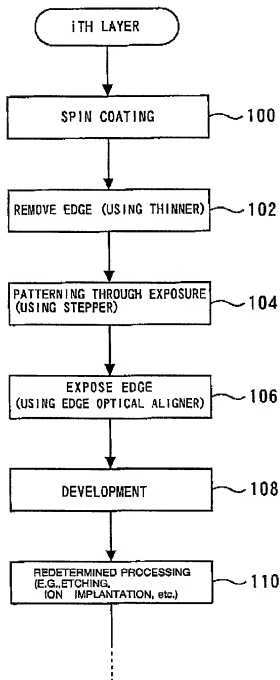


Fig. 4A

PRIOR ART

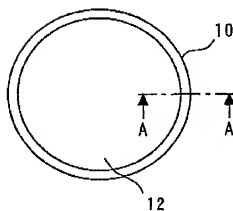


Fig. 4B

PRIOR ART

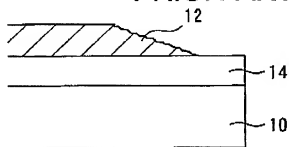


Fig.5

PRIOR ART



Fig.6A

PRIOR ART

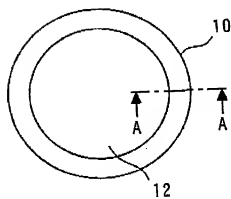


Fig.6B

PRIOR ART

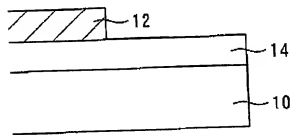


Fig.7

PRIOR ART

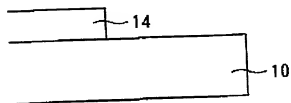


Fig. 8

PRIOR ART

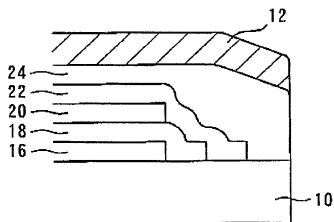


Fig. 9

PRIOR ART

